

10/01/00

Class	Subclass
-------	----------

TRUE CLASSIFICATION

PATENT NUMBER

U.S. UTILITY Patent Application

D.L.P.E.

PATENT DATE

SCANNED

Q.A.

APPLICATION NO. 09/901038	CONT/PRIOR F	CLASS 438 156	SUBCLASS 710	ART UNIT 1765	EXAMINER Walt <i>Crawell</i> <i>Deo</i>
------------------------------	-----------------	--------------------------------	----------------------------	------------------	--

TITLE

Toshihiro Yamashita
Hiroto Ise

345.28

Plasma processing system in which wafer is retained by electrostatic chuck, plasma processing method and method of manufacturing semiconductor device

ISSUING CLASSIFICATION

[illegible]

<input type="checkbox"/> TERMINAL DISCLAIMER	DRAWINGS		CLAIMS ALLOWED	
	Sheets Drwg.	Figs. Drwg.	Print Fig.	Total Claims
<input type="checkbox"/> The term of this patent subsequent to _____ (date) has been disclaimed. <input type="checkbox"/> The term of this patent shall not extend beyond the expiration date of U.S Patent. No. _____ _____ _____	_____ (Assistant Examiner) (Date)		NOTICE OF ALLOWANCE MAILED	
	_____ _____ (Primary Examiner) (Date)		ISSUE FEE	
			Amount Due	Date Paid
<input type="checkbox"/> The terminal _____ months of this patent have been disclaimed.	_____ (Local Instruments Examiner) (Date)		ISSUE BATCH NUMBER	

WARNING:

The information disclosed herein may be restricted. Unauthorized disclosure may be prohibited by the United States Code Title 35, Sections 122, 181 and 368. Possession outside the U.S. Patent & Trademark Office is restricted to authorized employees and contractors only.

Form PTO-436A
(Rev. 5/89)

FILED WITH: ☐ DISK (CRF) ☐ FICHE ☐ CD-ROM
(Attached in pocket on right inside flap)

BEST AVAILABLE COPY
(FACE)